

METHODS FOR AFFIRMING SWITCHED STATUS OF MEMS-BASED DEVICES

ABSTRACT OF THE DISCLOSURE

A configuration is provided by which it may be determined whether a MEMS device is in a select state. The select state is defined by a position of a moveable element, which is moved with electrostatic forces upon activation of an electrode. The select state is detected with a sensing configuration that has first and second regions. The regions are generally separated such that they are electrically uncoupled unless the moveable element is in the position that defines the select state. A detector may be provided to indicate whether the first and second regions are coupled electrically.

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